



PRESS RELEASE

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Qualiflow Introduces Piezo Valve for Use in New Deposition Technologies

Montpellier, France –July 22, 2002 – Qualiflow, a leading supplier of products for high purity gas control, today introduced a new product, the Piezo Injection Valve, designed to meet the increased thinning of films needed for atomic layer deposition (ALD) and other new technologies.

The Piezo Injection Valve was developed based on piezoelectric technology licensed from Siemens AG. It is based on a mature technology that was developed by Siemens over many years and was introduced to the semiconductor industry by Qualiflow.

“There are new deposition technologies, including ALD, which require extremely thin films,” said Claude Jacquemin, Qualiflow chairman. “Industry experts agree that these technologies will play a vital role in the manufacture of next generation chips. Qualiflow is very pleased to be able to support ALD technology development by offering a valve with the response speed that is required for these processes.”

The Piezo Injection Valve features a fast response time and a long lifespan due to a low alternate stress. Because of the speed and stability provided by piezoelectric technology, the valve offers unprecedented control of thickness, uniformity, quality and material properties of mono-layer films that are less than 100 angstroms thick.

Harnessing the power of piezoelectric technology for semiconductor processing has been a major initiative for Qualiflow over the past year. Thanks to innovative technology and know how, Qualiflow has an established portfolio of products that leverage this technology.

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The piezoelectric technology upon which the Piezo Injection Valve is based is the same technology used by Qualiflow in the New Generation Piezoelectric Valve MFC, which became the first cost competitive piezoelectric valve MFC for the semiconductor industry when it was introduced by Qualiflow in July 2001. The piezoelectric technology makes New Generation Piezoelectric Valve MFC ideal for 300 mm wafer processing, which requires more accurate and reliable flow control. This product is further enhanced when used along with the DeviceNet Stick, an innovative modulator combination of hardware and software that simplifies the monitoring and controlling of multiple gas lines. DeviceNet Stick provides control and monitoring of MFCs, pressure sensors, temperature sensors, pressure controllers, valves and pump/purge control logic.

About QUALIFLOW

QUALIFLOW is a world leading supplier of innovative solutions for ultra high purity gas control. Based in Montpellier, France, QUALIFLOW was formed in 1997 as the result of the spin-off of ASM International's component and gas systems line of business.

With sales figures of almost 19.3 M€ in 2001, QUALIFLOW plans to become a world leader in gas components. The company has approximately 90 employees worldwide and maintains a global network of technical centers in Montpellier; Tokyo, Japan; and Fremont, California. QUALIFLOW is traded under the code 7786 in the Paris Stock Exchange's Nouveau Marché.

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